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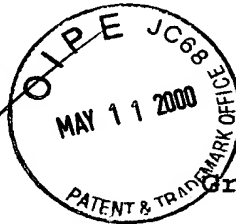
PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Kenji NISHI

Appln. No.: 08/994,758



Group Art Unit: 2851

Filed: December 19, 1997

Examiner: A. Mathews

For: PROJECTION EXPOSURE APPARATUS

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AMENDMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

In response to the Office communication dated April 11, 2000, please amend the above-identified patent application as indicated below.

IN THE CLAIMS:

Please add the following new claims:

- DI
- 1 --169. An exposure apparatus in which a portion of a
 - 2 pattern of an original is projected onto a substrate and in
 - 3 which the original and the substrate are scanned
 - 4 synchronously such that the pattern of the original is
 - 5 transferred to the substrate, said apparatus comprising:

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